

Title (en)

ASSEMBLIES AND METHODS FOR GUIDING RADIATION

Title (de)

ANORDNUNGEN UND VERFAHREN ZUR FÜHRUNG VON STRAHLUNG

Title (fr)

ENSEMBLES ET PROCÉDÉS DE GUIDAGE DE RAYONNEMENT

Publication

EP 3869270 A1 20210825 (EN)

Application

EP 20157939 A 20200218

Priority

EP 20157939 A 20200218

Abstract (en)

Apparatus and method for measuring one or more parameters of a substrate (300) using source radiation emitted from a radiation source (100) and directed onto the substrate. The apparatus comprises at least one reflecting element (710a) and at least one detector (720, 721). The at least one reflecting element is configured to receive a reflected radiation resulting from reflection of the source radiation from the substrate and further reflect the reflected radiation into a further reflected radiation. The at least one detector is configured for measurement of the further reflected radiation for determination of at least an alignment of the source radiation and/or the substrate

IPC 8 full level

G03F 7/20 (2006.01); **G01B 11/27** (2006.01); **G01N 21/956** (2006.01)

CPC (source: EP)

G01B 11/02 (2013.01); **G03F 7/70616** (2013.01); **G01B 2210/56** (2013.01); **G01N 21/956** (2013.01)

Citation (applicant)

- US 6952253 B2 20051004 - LOF JOERI [NL], et al
- US 2010328655 A1 20101230 - DEN BOEF ARIE JEFFREY [NL]
- US 2011102753 A1 20110505 - VAN DE KERKHOF MARCUS ADRIANUS [NL], et al
- US 2012044470 A1 20120223 - SMILDE HENDRIK JAN HIDDE [NL], et al
- US 2011249244 A1 20111013 - LEEWIS CHRISTIAN MARINUS [NL], et al
- US 2011026032 A1 20110203 - DEN BOEF ARIE JEFFREY [NL], et al
- EP 1628164 A2 20060222 - ASML NETHERLANDS BV [NL]
- US 45159908 A 20080220
- US 70867810 A 20100219
- US 25678008 A 20081023
- US 48644909 A 20090617
- US 92096809 A 20090320
- US 92258709 A 20090324
- US 200913000229 A 20090514
- US 201113033135 A 20110223
- US 201213533110 A 20120626
- US 201313891410 A 20130510
- WO 2011012624 A1 20110203 - ASML NETHERLANDS BV [NL], et al
- US 2016161863 A1 20160609 - DEN BOEF ARIE JEFFREY [NL], et al
- US 2016370717 A1 20161222 - DEN BOEF ARIE JEFFREY [NL], et al
- US 2007224518 A1 20070927 - YOKHIN BORIS [IL], et al
- US 2013304424 A1 20131114 - BAKEMAN MICHAEL S [US], et al
- US 2014019097 A1 20140116 - BAKEMAN MICHAEL S [US], et al
- US 2017184981 A1 20170629 - QUINTANILHA RICHARD [NL], et al
- US 2016282282 A1 20160929 - QUINTANILHA RICHARD [NL], et al
- LEMAILLET ET AL.: "Intercomparison between optical and X-ray scatterometry measurements of FinFET structures", PROC. OF SPIE, 2013, pages 8681, XP055267051, DOI: 10.1117/12.2011144

Citation (search report)

- [XII] EP 2698598 A1 20140219 - J A WOOLLAM CO INC [US]
- [XAI] US 7489399 B1 20090210 - LEE SHING [US]
- [XAI] US 2019094130 A1 20190328 - BLASENHEIM BARRY [US], et al
- [XAI] US 5166752 A 19921124 - SPANIER RICHARD F [US], et al
- [A] EP 3467588 A1 20190410 - ASML NETHERLANDS BV [NL]

Designated contracting state (EPC)

AL AT BE BG CH CY CZ DE DK EE ES FI FR GB GR HR HU IE IS IT LI LT LU LV MC MK MT NL NO PL PT RO RS SE SI SK SM TR

Designated extension state (EPC)

BA ME

DOCDB simple family (publication)

EP 3869270 A1 20210825

DOCDB simple family (application)

EP 20157939 A 20200218